

<b>Notice of References Cited</b>		Application/Control No. 10/622,607	Applicant(s)/Patent Under Reexamination CHEN ET AL.	
		Examiner Matthew W. Such	Art Unit 2891	Page 1 of 1

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*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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C	US-			
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J	US-			
K	US-			
L	US-			
M	US-			

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**NON-PATENT DOCUMENTS**

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U	Merriam-Webster's Collegiate Dictionary. 10th ED. (1997): entry for "lithography".
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a))  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.